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OFFICE OF PETITIONS

Docket No.: 9323.054.00-US
(PATENT)

#11

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

In Kwon JEONG

Application No.: 09/839,508

Filed: April 20, 2001

For: APPARATUS AND METHOD FOR
SEQUENTIALLY POLISHING AND
LOADING/UNLOADING SEMICONDUCTOR
WAFERS

Confirmation No: 2893

Art Unit: 3723

Examiner: Berry, W.

Customer No.: 30827

RESPONSE TO RESTRICTION/ELECTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In response to the restriction/election requirement set forth in the Office Action dated January 29, 2002, Applicant hereby elects to prosecute Group I, claims 1-22 and 38-40 without traverse.

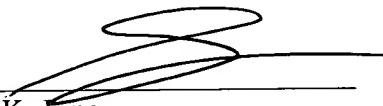
The Applicant believes each of the claims in elected Group I is in condition for allowance. Notice of same is earnestly solicited. If the Examiner believes that a telephone call would further the prosecution of the present application, the Examiner is encouraged to contact the Applicant's representative at the telephone number provided herein below.

Applicants hereby authorize the Commissioner of Patents to charge any fees necessary to complete this filing, including any fees required under 37 C.F.R. §1.136 for any necessary Extension of Time to make the filing of the attached documents timely, or credit any overpayment in fees, to Deposit Account No. 50-0911. Further, if these papers are not

considered timely filed, then a petition is hereby made under 37 C.F.R. §1.136 for the necessary extension of time.

Dated: May 6, 2004

Respectfully submitted,

By 
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